

Customer No. 22,852 Attorney Docket No. 04329.2620-01

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

in re Application of:	)
Hiroshi NOMURA et al.	) Group Art Unit: 2851
Application No.: 10/657,251	) Examiner: Alan A. MATHEWS
Filed: September 9, 2003	) )
For: EVALUATION MASK, FOCUS MEASURING METHOD AND ABERRATION MEASURING METHOD	) Confirmation No.: 4036 ) )
Commissioner for Patents P.O. Box 1450	• .

Alexandria, VA 22313-1450

Sir:

## **AMENDMENT**

In reply to the Office Action mailed December 16, 2004, the period of response extending through March 16, 2005, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims in this paper. Remarks/Arguments follow the amendment sections of this paper.